Electrons and holes contribute to the charge transport in for most of the important semiconductor materials.<br>
Semiconductors, while ordinary charge transport in metals is The basic phenomena of high field transport are non semiconductors, while ordinary charge transport in metals is metals because of their high electrical conductivity and the heterojunctions between different semiconductors (6). necessity of the presence of high currents according to Ohm's In semiconductor devices, the high field effects are based densities of the order of  $10^5$  A/cm<sup>2</sup>, or even much lower, demay approach zero. Ryder and Shockley noticed (1,2) that

of current density to fields were measured in germanium at room temperature for fields as small as 1000 V/cm.

High field transport in semiconductors became then an area of considerable research. It was found that the nonlinear behavior (the deviation from Ohm's law) was due to an elevation of the energy of the charge carriers caused by the accelerating force of the electric field. Interactions with the lattice vibrations lower the energy of the charge carriers as Joule heat is transferred to the crystal lattice. However, electric fields always cause a finite rise of charge carrier energy above the equilibrium energy (corresponding to the temperature of the crystal lattice). This excess energy can sometimes also be described by a temperature, the temperature  $T_c$  of the charge carriers, which is larger than the temperature  $T<sub>L</sub>$  of the crystal lattice. One speaks therefore of *hot carrier transport* in semiconductors.

The rise in charge carrier energy changes the conductance for two reasons. For one, a higher energy gives rise to significant changes in the interactions of the charge carriers with crystal imperfections that form scattering centers. The scattering rate influences the conductance directly. Increases or decreases of this rate lead to decreases or increases of the conductance, respectively. The second reason for variations in conductance with charge carrier energy arise from changes in the  $E(\mathbf{k})$  relation. This function gives the connection between the energy  $E$  and the wave vector  $\boldsymbol{k}$  of the charge carriers, which corresponds in classical mechanics to the energy– momentum relation. Since conductance is a sensitive function of  $\partial E(\mathbf{k})/\partial k$ , it changes with the energy of the electrons (or with  $T_c$  whenever a temperature of the carriers is well defined).

The most complete existing theory of high field transport in semiconductors involves the solution of a Boltzmann type equation (3). The use of this equation can be justified by invoking the dephasing of quantum coherence over distances that correspond to the feature sizes of semiconductor structures and devices. Consequently, the charge carriers do behave classically and can, in a way, be understood from the principles of classical mechanics. Quantum mechanics has then only a background role and determines, for example, the effective mass or the velocity of the electrons or gives justification to the existence of holes and hole transport. Fermi's ''golden rule'' of quantum mechanics is used to calculate the scattering rates and thus represents another quantum contribution. It is also easy to include the Pauli principle in such an equation and thus to approach some properties of a Fermi liquid. However, the assumption of weak perturbational in-**HIGH-FIELD EFFECTS** teraction of the particles, which is basic to Boltzmann's derivation, must remain true, and indeed is a good approximation

restricted to electrons only. Another distinctive feature of conductance (3); changed responses to magnetic fields (4); semiconductor transport is its inherent nonlinearity in high changed high-frequency response, including the dielectric electric fields. It is difficult to generate high electric fields in function (5); and changed confinement in potential wells or at

law. In semiconductors, high fields can exist with current on the same phenomena. For example, in transistors of the field effect family, the electric fields can be as high as  $10<sup>5</sup>$ pending on their conductance, which at low temperatures  $V/cm^2$  and the corresponding carrier temperatures may reach  $T_c = 10^4$  K (7). Such temperatures cause changes in the consemiconductor electron transport was extremely nonlinear in ductivity by orders of magnitude (mostly reductions) (3,5). Rehigh electric fields. Strong deviations from the proportionality member that  $T_c$  is the temperature of the charge carriers and

not of the crystal lattice, which would melt at such temperatures.  $T<sub>L</sub>$ , the temperature of the crystal lattice, can also be raised, but is usually raised orders of magnitude less. This difference is possible because the systems of electrons and crystal lattice are only weakly coupled. Under certain circumstances the conductance can also be raised by hot electron phenomena, leading to speed advantages in devices (e.g. velocity overshoot phenomena) (8). Devices made of semiconductor heterojunctions also exhibit various forms of hot electron transfer (e.g. real-space transfer) between the different materials. These effects often give rise to a device performance degradation, but also can be used advantageously (6).

In the following, a general theory of high field transport is developed. The next section describes high field transport in bulk semiconductors (theory and experimental results), and finally an overview of major effects in devices is given.

# **THE BOLTZMANN EQUATION FOR HIGH FIELD SEMICONDUCTOR TRANSPORT**

The following is a top-down approach to the theory of high field phenomena. The next section derives a modern Boltzmann equation including the most important quantum effects as derived from the energy band structure. The relevance of the various terms of this equation to hot electron phenomena<br>are discussed and general ways to obtain solutions are briefly<br>reviewed and referenced. Subsequently a more phenomeno-<br>logical discussion and analytical approxi

# **Derivation of a Modern Boltzmann Equation** trons with velocity  $v$  is  $v_x dt$ , we have

The Boltzmann equation derived here is more general than incoming:  $f(\mathbf{k}, \mathbf{r}, t) d\mathbf{k} dy dz v_x dt$  (1) the original equation derived by Boltzmann. The only cases of weakly interacting charge carriers in solids that cannot be outgoing:  $f(\mathbf{k}, (x+dx, y, z), t) d\mathbf{k} dy dz v_x dt$  (2) understood from this modified equation are those that involve macroscopic feature sizes (e.g., device boundaries) that are and the net particle gain is smaller than the quantum dephasing length under the given conditions. This dephasing length in silicon at room temperature is of the order of several hundred angstrom, but can be much smaller in high electric fields, approaching 20 Å for electron energies of about 1.5 eV. This means that for conven tional devices operating with high fields, hot electron transport can be understood extremely well with the theory devel- in 3 dimensions. oped below even if the feature sizes are below 100 Å. Note that the velocity  $v$  is here equal to the group velocity Quantum effects such as tunneling can often be added to this theory by the Bardeen transfer Hamiltonian formalism (3,9).

The following derivation lacks complete mathematical electrons and therefore on how "hot" the electrons are. It also rigor but is valid under widely varying circumstances. For ex-<br>describes diffusion since concentration gr rigor but is valid under widely varying circumstances. For ex-<br>algorithms diffusion, since concentration gradients enter this<br>ample, we need not assume conservation of the number of term. The relation between diffusion and ample, we need not assume conservation of the number of term. The relation between diffusion and electron heating is<br>particles, which is important in that electrons and holes can actually a complicated one and will be disc annihilate each other or can be created by light. We follow nomenologically.<br>Boltzmann, but replace the velocity in seven-dimensional In analogous Boltzmann, but replace the velocity in seven-dimensional In analogous manner, we obtain the change of the number<br>phase space by the wave vector **k** in the definition of a distriction of electrons at **k** in **k** space becau phase space by the wave vector **k** in the definition of a distri-<br>bution function  $f(k, r, t)$ , meaning as usual the probability of ing  $dr$  by  $dk$  etc. as illustrated in Fig. 1, and replacing finding charge carriers at  $\boldsymbol{k}$ ,  $\boldsymbol{r}$  and at time  $t$  in the volume elements *dk*, *dr*, *dt*. Consider then a cube in *r* space and in *k* space as shown in Fig. 1.

We first calculate how many electrons arrive from the left and enter the cube through the left *dy dz* plane, and how many leave at the corresponding plane on the right, all during a time period *dt*. Since the *x*-direction travel distance of elec- represents the major energy supply to the electrons and



$$
-v_x[f(\mathbf{k}, (x+dx, y, z), t) - f(\mathbf{k}, \mathbf{r}, t)] dy dz d\mathbf{k} dt
$$
  
= 
$$
-v_x \frac{\partial f}{\partial x} dx dy dz d\mathbf{k} dt
$$
  
= 
$$
-v \cdot \nabla f d\mathbf{k} dr dt
$$
 (3)

and is related to *k* by  $v = \nabla_k E(\mathbf{k})/\hbar$  (3).

theory by the Bardeen transfer Hamiltonian formalism  $(3,9)$ . This balance depends on the velocity and *k* vector of the<br>The following derivation lacks complete mathematical electrons and therefore on how "hot" the electr actually a complicated one and will be discussed below phe-

> ing  $dx$  by  $dk_x$  etc. as illustrated in Fig. 1, and replacing  $dx/dt = v_x$  as used in Eq. (1) by  $dk_x/dt$ , one gets

$$
-\frac{d\mathbf{k}}{dt} \cdot \nabla_{\mathbf{k}} f \, d\mathbf{k} \, dr \, dt \tag{4}
$$

where  $d\hbar/dt = -e\mathbf{F}$  (3) and **F** is the electric field. This term

fects. as discussed above, we arrive then at

There is still another possibility to change the number of electrons with wave vector *k* at *r*. The electrons can be scattered and change their wave vector from  $\boldsymbol{k}$  to  $\boldsymbol{k}'$  at a given point  $r$  in real space. Figure 2 shows the two infinitesimal volumes in *k* space to illustrate the scattering events. The outgoing (out of state *k*) electrons are

$$
out = -\sum_{\mathbf{k}'} S(\mathbf{k}, \mathbf{k}') f(\mathbf{k}, \mathbf{r}, t) d\mathbf{k} d\mathbf{r} dt
$$
 (5)

to be in the *k* state to be scattered out. In degenerate systems cluded in the band structure and then are automatically (Fermi statistics), an additional factor  $1 - f(k', r, t)$  arises taken into account in the distribution function f once the from the Pauli principle. The incoming (into the *k* state) elec- Boltzmann equation is solved. From the distribution function,

$$
\text{in} = \sum_{\mathbf{k}'} S(\mathbf{k}', \mathbf{k}) f(\mathbf{k}', \mathbf{r}, t) \, d\mathbf{k} \, d\mathbf{r} \, dt \tag{6}
$$

$$
\frac{\partial f(\mathbf{k}, \mathbf{r}, t)}{\partial t} = -\mathbf{v} \cdot \nabla f(\mathbf{k}, \mathbf{r}, t) - \frac{1}{\hbar} \mathbf{F}_0 \cdot \nabla_{\mathbf{k}} f(\mathbf{k}, \mathbf{r}, t) + \sum_{\mathbf{k}'} [f(\mathbf{k}', \mathbf{r}, t) S(\mathbf{k}', \mathbf{k}) - f(\mathbf{k}, \mathbf{r}, t) S(\mathbf{k}, \mathbf{k}')] \tag{7}
$$



ters from a volume  $dk_x dk_y dk_z$  at *k* to another such volume at  $k'$ . tion, precise and explicit solutions can be found only under

therefore the root cause of the heating and hot electron ef- If we include the factors arising from the Pauli principle

$$
\frac{\partial f(\boldsymbol{k}, \boldsymbol{r}, t)}{\partial t} = -\frac{1}{\hbar} \nabla_{\boldsymbol{k}} E(\boldsymbol{k}) \cdot \nabla f(\boldsymbol{k}, \boldsymbol{r}, t) - \frac{1}{\hbar} \boldsymbol{F}_0 \cdot \nabla_{\boldsymbol{k}} f(\boldsymbol{k}, \boldsymbol{r}, t) \n+ \sum_{\boldsymbol{k}'} \{ f(\boldsymbol{k}', \boldsymbol{r}, t) [1 - f(\boldsymbol{k}, \boldsymbol{r}, t)] S(\boldsymbol{k}', \boldsymbol{k}) \n- f(\boldsymbol{k}, \boldsymbol{r}, t) [1 - f(\boldsymbol{k}', \boldsymbol{r}, t)] S(\boldsymbol{k}, \boldsymbol{k}') \}
$$
\n(8)

This equation is very general and includes automatically, for example, effects of the energy band structure as described by  $E(\mathbf{k})$ . Of course, it describes transport in one band only (3). The functional form of this band, however, can be arbitrary. The factor  $f(\mathbf{k}, \mathbf{r}, t)$  is necessary because an electron has first Effects of strain in the solid, for example, need only be introns are one can in turn obtain macroscopic quantities such as the electronic current in the usual prescribed way.

To summarize, all terms of this equation have special significance for hot electron effects. The second term on the right-hand side (RHS) of Eq. (8) represents the driving force, Again, the Pauli principle will call for a factor  $1 - f(k, r, t)$ .<br>The electric field **F**, and signifies the heating of the electrons.<br>The in and out scatterings lead to a (more or less) random<br>distribution of the **k** vector. (temperature).<br>
The Boltzmann equation describes all of these heating-<br>
the set of conjug dynamics and is obtained by balancing the p cates that the hot electron diffusion not only is dependent on the heating of the electrons but in turn influences the heating. This term is relevant to the question of how the force heats the electrons. For example, a confining force that does not give rise to a current (as, e.g., at a potential minimum) may not heat the electrons, since for this case the accelerating where  $\mathbf{F}_0$  is the force ( $-e\mathbf{F}$  for an electric field  $\mathbf{F}$ ). can cancel exactly (10,3,11).

> The energy band structure enters the Boltzmann equation through the  $E(\mathbf{k})$  relation in the first term on the RHS. It also enters indirectly through the sum over *k*, since this sum includes the density of states. Finally, if one wants to calculate a current, one needs to integrate the product of velocity and distribution function over all **k** space, where the velocity is given by  $\mathbf{v} = \nabla_{\mathbf{k}} E(\mathbf{k})/\hbar$ .

> A full solution of the Boltzmann equation as derived above does describe all hot electron phenomena currently known in semiconductors. It can be and has been achieved numerically in bulk semiconductors (12) and in devices (13). We refer the reader to these references and to software and explanations available on Web sites (14). Here we continue with discussions of important experimental results in terms of approximate concepts and solutions.

## **Approximate Solutions of the Boltzmann Equation and Hot Electrons**

Figure 2. Schematic of a scattering process. The charge carrier scat-<br>Since the Boltzmann equation is an integrodifferential equa-

very special circumstances. The best-known example is the time-independent solution for homogeneous systems (no space-dependent terms) in the relaxation time approximation. Under the assumption of weak forces (electric fields), one can write the distribution function as a sum of a function  $f_0$  that is even in the wave vector  $\boldsymbol{k}$  and an odd function  $f_1$ . Assuming that the Pauli terms are negligible, as they are for not too high carrier concentrations, the whole collision integral of Eq. (8) reduces then to

$$
collision integral = f_1 / \tau_{tot}
$$
 (9)

$$
\frac{1}{\tau_{\rm tot}} = \sum_{\boldsymbol{k}'} S(\boldsymbol{k}, \boldsymbol{k}') \tag{10}
$$

$$
f_0=\exp(E_{\rm F}/kT_{\rm L})\exp(-E/kT_{\rm L})\eqno(11)
$$

$$
f_1 = -\tau_{\text{tot}} \frac{\boldsymbol{F}_0}{\hbar} \cdot \nabla_{\boldsymbol{k}} e^{(E_{\text{F}} - E)/kT} \tag{12}
$$

$$
j = -\frac{e}{4\pi^3} \int \mathbf{v} f_1 d\mathbf{k} \tag{13}
$$

The high field or hot electron term is neglected in this approach, which describes only low fields and ohmic behavior. where  $k_B$  is Boltzmann's constant. The actual solution of the The reason is the approximation of  $f_0$  by the equilibrium dis-<br>Boltzmann equation to arrive at t resulting for both  $f_0$  and  $f_1$  in the relaxation time approxima- An approximate formula for  $T_c$  is (3) tion. As described above, the force accelerates the electrons (holes), and the scattering randomizes, thus causing  $f_0$  to contain more energetic electrons and therefore changing its form away from the equilibrium.

As mentioned, the complete solution of Eq. (8) has been achieved by so-called Monte Carlo methods, which are related  $F_c$  is a critical electric field that is around  $10^4$  V/cm for silicon to the Monte Carlo integration known from numerical mathe- at room temperature. The carrier temperature  $T_c$  can therematics (3,5). These solutions have been described at length in fore become extremely high. For example, at the field  $F =$ 

Approximate solutions of the Boltzmann equation for high electric fields are also well known. Of particular importance is the electron temperature approximation, which is described sured by various methods that can sense the electron energy in the next section together with typical experimental results inside the semiconductor (15). An outside touch does not refor high field transport in bulk (homogeneous) semicon- veal a temperature increase of the electrons, because of the ductors. large work function that the electrons would need to overcome

semiconductor transport was given by the work of Shockley change in the scattering rate that enters the mobility  $\mu$  of the



**Figure 3.** Current density (or drift velocity) versus electric field in bulk *n*-type germanium for three temperatures (as indicated). Notice and  $f_0$  being equal to the equilibrium Boltzman distribution the saturation at electric fields above 10<sup>3</sup> V/cm. (After Ref. 1.) Regiven by printed with permission,  $\circ$  1953 by the American Physical Society.

The odd part of the distribution function that determines the  $(1951)(2)$  and Ryder (1953) (1), who found a saturation of the electric current is then  $V/cm$  as shown in Fig. 3. This current saturation is basic to hot electron phenomena and has been shown to arise from the *f* increase of average electron energy  $\langle E \rangle$ . Under certain assumptions that are approximately satisfied in *n*-type silicon with  $E_F$  being the Fermi level. The electric current density jard germanium for intermediate electric fields (3), one can<br>is then obained from the average energy by a temperature  $T_c$ , which, for<br>not too high electron de Boltzmann type formula:

$$
\langle E \rangle = \frac{3}{2} k_{\rm B} T_{\rm c} \tag{14}
$$

The reason is the approximation of  $f_0$  by the equilibrium dis-<br>tribution. To allow for high electric fields, one needs to solve<br>the full Boltzmann equation or at least the coupled equations<br>detailed information.

$$
T_c \approx T_L \left[ 1 + \left(\frac{F}{F_c}\right)^2 \right] \tag{15}
$$

the literature and form a vast field (5,12,13,14).  $2 \times 10^4$  V/cm, which can easily be reached and indeed is routinely reached in modern transistors, we have  $T_c = 1500$  K for  $T_L = 300$  K. Such temperatures have indeed been meain order to propagate out of the semiconductor (16). Equation (11) is not valid for much higher electric fields than  $3 \times 10^4$ **HOT ELECTRON EFFECTS IN SEMICONDUCTORS**<br>AND APPROXIMATE THEORY<br>AND APPROXIMATE THEORY<br>The original parabolicity (5). For very high fields, a full band Monte Carlo approach is again necessary to calculate the average energy **Electron Temperature and Scattering Rate** and distribution functions of the electrons reliably.

A first glimpse of how important hot electrons would be in The rise of the electron temperature (or energy) causes a

charge carriers and therefore the conductivity  $\sigma = en\mu$  (*n* betionally. and a large framework of research exists (7,18).

$$
\mu \approx \mu_0 \left(\frac{T_{\rm L}}{T_{\rm c}}\right)^{1/2} \tag{16}
$$

where  $\mu_0$  is the mobility at zero electric field, i.e. for  $T_L = T_c$ . mation. Using, then, the equation for the current density of a homoge-<br>Using, then, the current density of a homoge-<br>sense a homogeneous comparation for the current density of a homogeneous comparation of band structure and relat

$$
j = en\mu_0 \left(\frac{F}{1 + (F/F_c)^2}\right)^{1/2} \tag{17}
$$

current saturation (nonlinear transport) at high electric fields effect are mostly determined by the structure of the  $E(\mathbf{k})$  rela-<br>and is quite general. For example, the square root in Eq. (16) tion, i.e. by effects in and is quite general. For example, the square root in Eq. (16) tion, i.e. by effects in *k* space. The terms of the Boltzmann derives from the density of states. Equation (17) is valid even equation signifying real-space o derives from the density of states. Equation (17) is valid even equation signifying real-space operations have not been dis-<br>for a more general density of states: it can be proven easily cussed yet. From the discussions fo for a more general density of states; it can be proven easily cussed yet. From the discussions following Eq. (8) it is clear, for any density of states that is proportional to  $E^p$  for any however, that real-space effect for any density of states that is proportional to  $E^p$  for any  $p > 0$ . The dependence of the electron phonon scattering rate port significantly. The prime reason for this complication is on the density of states is illustrated below (Fig. 9). Note, the real-space transfer effect (6), on the density of states is illustrated below (Fig. 9). Note, however, that in devices other scattering mechanisms such as The transfer of electrons between two different solids is surface roughness scattering are of great importance. Some of known from Bethe's thermionic emission theory (3). This type these mechanisms are reviewed in Ref. 16. of transport includes only electric fields perpendicular to the

The derivation of Eq.  $(17)$  contains only changes in the scattering rate with carrier temperature. As mentioned above, however, the band structure influences not only the scattering rate (via the density of states) but also the velocity *v* of the electrons, since in the one-band approximation we have (3)

$$
\mathbf{v} = \frac{1}{\hbar} \nabla_{\mathbf{k}} E(\mathbf{k}) \tag{18}
$$

For the typical band structure of some III–V compounds, this leads to pronounced effects in the current–voltage characteristics. For GaAs, the effective mass is small at low energies ( $m^* = 0.067m_0$ ) and  $E(\mathbf{k}) = \hbar^2 k^2 / 2m^*$ . Correspondingly, the velocity of electrons becomes very high at moderate energies. However, the band structure changes drastically only 0.3 *F* (arbitrary units) eV above the conduction band edge, exhibiting there additional minima with much higher effective mass (close to the<br>germanium type conduction), and above 0.5 eV, even higher<br>effective masses (close to the silicon conductio available as the energy increases and each one exhibiting and electric field they can even cross. However, they are always close higher mass. If the electrons are heated by electric fields, they at very high fields.

initially are on the fastest highway, exhibiting a high mobility ing the carrier concentration). The mobility derives from the and conductance. At higher fields they are heated enough to relaxation time as defined in Eq. (10) if the scattering is ran- transfer to the germaniumlike conduction band minimum domizing (independent of the wave vector). Otherwise  $\tau_{tot}$  (highway 2) and at still higher fields to the siliconlike minineeds to be replaced by the so-called momentum relaxation mum (highway 3). This decreases their speed so drastically time (3). This relaxation time usually exhibits a significant that GaAs actually shows a range of negative differential reenergy dependence. For phonon scattering it decreases typi- sistance, i.e., the current drops as the electric field is incally with increasing energy, while for scattering by weakly creased. This phenomenon leads to the Gunn effect, which screened Coulomb charges it increases. The mobility  $\mu$  is pro- manifests itself by high-frequency current oscillations, since portional to a weighted energy average of the relaxation time, the situation of negative differential resistance is not stable and the conductivity therefore increases or decreases propor- (7). These phenomena have received considerable attention,

A typical dependence of the mobility on the electron tem- The current–field characteristic of GaAs is shown in Fig. 4 perature is then (for the case of scattering by phonons) (3) and compared with the characteristics of silicon (both for electron transport). It is evident that the low field current behavior of GaAs transforms into siliconlike behavior at high electric fields, with a region of negative differential resistance in between. The reader is referred to Refs. (3,5,7) for more infor-

neous semiconductor,  $j = en\mu$ , one gets from Eq. (16) and direct experimental verification of band structure and related Eq.  $(15)$   $E<sub>1</sub>(15)$  semiconductor parameters for high-field transport. Optical measurements and femtosecond spectroscopy (19) do give detailed information on the density of states.

## **Real–Space Transfer**

This equation shows immediately the essential feature of The negative differential resistance of GaAs and the Gunn<br>rrent saturation (nonlinear transport) at high electric fields effect are mostly determined by the structu

different layers of semiconductors. However, electric fields **Effects of Band Structure and the Gunn Effect** parallel to semiconductors can energize the charge carriers (hot electron effect) and lead to a redistribution of them in





Figure 5. Electrons in a material with lower conduction band edge<br>
(e.g., GaAs) neighboring two layers with higher conduction band edge<br>
(e.g., AlAs) accelerated by a force  $\mathbf{F}_0$ . The electrons gain energy and<br>
are sc

of the conduction band edges of the various materials. (Read- by Luryi and Kastalsky (6)].<br>ers not used to solid state concepts should think of the con- The real-space transfer effect is also of general importance ers not used to solid state concepts should think of the con-<br>duction hand edge as the minimum kinetic energy of conduc- in all situations when electrons are confined in potential wells duction band edge as the minimum kinetic energy of conduction electrons, which is different in different materials, the and parallel fields are applied (and accelerate the charge car-<br>electrons thus having different notential energy in each materials, even if the electrons do no electrons thus having different potential energy in each mate- riers), even if the electrons do not propagate out of the wells<br>rial). The effect of redistribution of electrons or holes due to but merely redistribute themse rial). The effect of redistribution of electrons or holes due to but merely redistribute themselves within each well. This is<br>electric fields parallel to different layers of semiconductors is of relevance for the understan electric fields parallel to different layers of semiconductors is of relevance for the understanding of the influence of trans-<br>called real-space transfer (BST) and is shown schematically verse fields (such as the gate fie called real-space transfer (RST) and is shown schematically verse fields (such as the gate field) in a transistor (10). The<br>in Fig. 5. This transfer of electrons (heated by parallel fields) RST effect and the spreading of in Fig. 5. This transfer of electrons (heated by parallel fields) RST effect and the spreading of the electrons are then deter-<br>over barriers is more complicated and more difficult to under-<br>mined by the transverse field. over barriers is more complicated and more difficult to under- mined by the transverse field. The quantum analog of this stand than other effects basic to nonlinear semiconductor classical picture is the redistribution of stand than other effects basic to nonlinear semiconductor classical picture is the redistribution of hot electrons in the reason is that RST can different quantized subbands of a quantum well. transport and device operation. The reason is that RST can be visualized only by the combination of two concepts related to the energy distribution of electrons. The first concept is **Time Dependences, Velocity Overshoot, and Ballistic Transport**

$$
f_0 = \exp(-E/kT_1) \tag{19}
$$

$$
f_0 \propto \exp\left(-\frac{\Delta E_c + E}{kT_{\rm L}}\right) \tag{20}
$$

Here the energy is measured from the GaAs conduction band edge, and  $\nabla E_c$  is the band edge discontinuity between AlAs and GaAs. where **F** is the electric field and  $\hbar \mathbf{k}$  is the crystal momentum.

to the layers, we have to replace  $T_L$  in Eqs. (19) and (20) by a described in Ref. 20, but is applicable under most circumspace-dependent carrier temperature  $T_c$ . It is clear that for stances. Neglecting the basic thermal motion of the electrons  $T_c \rightarrow \infty$  the difference between the AlAs and the GaAs popula- (due to  $T_L$ ), this means that all electrons are accelerated in tion densities vanishes. In other words, the electrons will the direction of the force and gain speed according to Eq. (18) spread out into the AlAs layers. This also means that even and Eq. (21). Since all electrons move in the same direction, perpendicular to the layers (*z* direction) a constant Fermi the average velocity is very large compared to the thermal level cannot exist, and  $E_F$  has to be replaced by the quasi- case where electrons move in all directions and have just a Fermi level  $E_{\text{QF}}(z)$  as the density of electrons becomes a func- small average drift velocity on top of the thermal motion. In tion of  $T_c(z)$ . This is unusual, since commonly the quasi-Fermi high electric fields, and with high values of  $T_c$ , the thermal levels differ only in the direction of the applied external volt- velocity (pointing randomly in all directions) can be as high age  $V_{\text{ext}}$  (by the amount  $eV_{\text{ext}}$ ). In the present case, a voltage as  $10^8$  cm/s, while the saturated drift velocity is (in silicon) a

is applied parallel to the layers, the electrons redistribute themselves perpendicularly to the layers, and a field (and voltage perpendicular to the layers) develops owing to the carrier redistribution. Basic to the calculation of this process are the thermionic emission currents (3) of hot electrons from one layer to the other. Since the external voltage is applied parallel to the layers, we have in steady state a precise balance of currents flowing from left to right and right to left, which

exhibiting real-space transfer.  $\frac{1}{2}$  terial system and electric fields of the order of  $10^3$  to  $10^4$  V/cm parallel to the layers, one obtains time constants of the order of picoseconds for the transfer, which gives the RST effect imthe different layers that depends sensitively on the difference portance for device applications [RST transistors as developed of the conduction band edges of the various materials (Read- by Luryi and Kastalsky (6)].

that of quasi-Fermi levels (3), and the second is the concept<br>of a charge carrier temperature  $T_c$  as already discussed above.<br>For RST problems, both concepts matter, and both the carrier<br>Fermi space and  $k$  space are alr

ality implies the validity of the Boltzmann equation, which, as discussed at the beginning, involves the dephasing of the while in the AlGaAs we have  $\frac{1}{100}$  wave function. For times much shorter than  $\tau_{\text{tot}}$ , the transport is essentially *ballistic,* which means that in crystalline semiconductors the accelerations are described by the equation

$$
\hbar \frac{d\boldsymbol{k}}{dt} = -e\boldsymbol{F} \tag{21}
$$

If now the electrons are heated by an external field parallel This equation becomes invalid at extremely short times, as

factor of ten below this value. A visualization of these facts is given in Fig. 6.

The range between the high-velocity ballistic transport and the low-velocity diffusive transport is called the range of velocity overshoot. Imagine transport in a semiconductor switched on at a time  $t_0 = 0$  by application of a high field *F*. The electrons are then accelerated ballistically for about 100 fs and may reach a velocity well above  $10<sup>7</sup>$  cm/s (the value of the saturated velocity in silicon and other important semiconductors). Then, as time goes on, scattering events randomize the velocity to all directions, which leads, typically after a picosecond or so, to the saturated average velocity. At the times in between, the velocity is higher and exhibits the overshoot. In GaAs these effects are accentuated by the change in effective mass at high energy, and the overshoot can be considerable (8). This is shown in Fig. 7.

A similar effect is also achieved for transport in short semiconductor sections sandwiched in between contacts. As soon as the electrons enter the semiconductor from the contact, they are accelerated by high electric fields into the overshoot or even the ballistic regime and leave the semiconductor, entering the second contact, before scattering can randomize their motion. Thus the velocity in short semiconductor diodes can overshoot the saturated value (now for all times), which in some devices gives a speed advantage (22).

## **Changes of Carrier Concentration and Hot Electrons: Impact Ionization**

Up to now, all the conductivity changes we have discussed have arisen from changes in the carrier velocity and a redistribution of charge carriers in energy. The total number of electrons or holes was not affected by hot electron effects. There exists, however, an important phenomenon that causes considerable changes of conductance because of changes in the total number of charge carriers. This is the occurrence of



Figure 6. Schematic of the development of average drift velocity versus time, assuming that a high electric field *F* is suddenly applied at  $t = 0$ . The electrons are accelerated to high velocities and high average drift velocities. Their random velocity (indicated by arrows pointing in all directions) is at first small but is steadily increased due to This increase of current with time also gives rise to a spatial randomizing scattering. At a certain point the average drift velocity increase of th approaches a maximum. From here on the random component of the velocity increases due to the very strong scattering at the high ener-<br>gies that the charge carriers now have, and the average drift velocity decreases. Finally, steady state is reached, where the scatterings and accelerations balance each other. The large random arrows indicate (at  $10^7$  cm/s in silicon).



**Figure 7.** Overshoot of electrons injected with certain wave vectors  $k_x$  in the *x* direction and with certain energies  $E_0$  into GaAs. A field  $F$ subsequently accelerates them and leads to velocity overshoot (19).

impact ionization, the exact inverse of the Auger effect (3). A heated electron in the conduction band (the same can be argued for holes) gains energy from the applied electric field and then collides with an electron in the valence band, lifting this electron up to the conduction band, with the net result of two conduction electrons and a hole. The primary electron and the secondary electron plus hole all contribute now to the conduction, and the electronic current density *j* therefore increases with time according to the equation

$$
\frac{d\boldsymbol{j}}{dt} = \alpha_t \boldsymbol{j} \tag{22}
$$

$$
\nabla \mathbf{j} = \alpha_{\mathbf{r}} \mathbf{j} \tag{23}
$$

The coefficient  $\alpha_r$  is in general a matrix. However, for a conthen a high electron temperature, and the drift velocity is saturated stant electric field impact ionization is mostly isotropic and  $\alpha_r$  is a scalar (12,23).

We will concentrate, in the following on the theory of  $\alpha_t$ . The theory of  $\alpha_r$  proceeds very similarly, and one can almost always use  $\alpha_i v_d = \alpha_r$ , where  $v_d$  is the average (drift) velocity of the electrons. The multiplication of electrons (and holes) with time depends physically on two quantities. One is the actual ionization probability, that is, the probability for an electron with given energy to create an electron–hole pair. This probability per unit time is called the impact ionization rate  $R<sub>1</sub>$ . The second quantity is the actual probability of having such an electron at a given energy, which is, of course, given by the distribution function.  $\alpha_t$  is then the average product of these two probabilities:

$$
\alpha_t = \frac{\int_{-\infty}^{\infty} d\mathbf{k} R_1 f}{\int_{-\infty}^{\infty} d\mathbf{k} f}
$$
(24)

The calculation of  $R<sub>I</sub>$  involves the quantum mechanics of three particles (two electrons, one hole) in two different bands **Figure 9.** Electron energy distribution as a function of electron en- (conduction and valence) with different (Bloch) wave func- ergy (in the conduction band), according to Ref. 24, for various contions and  $E(k)$  relations. Even using the approximate "golden stant electric fields. Also shown is the electron–phonon scattering. rule'' of time-dependent perturbation theory involves then a difficult numerical simulation with multiple integrations.<br>Most of the theories of the past are therefore oversimplified<br>and of very limited use, including the formula derived by Kel-<br>dysh (24). The only theory in reasonab experiments is the Monte Carlo integration of the "golden that matters for impact ionization. This high-energy tail de-<br>rule" formulae by Kane (25), the result of which is shown in pends sensitively on the band structure a rule" formulae by Kane (25), the result of which is shown in pends sensitively on the band structure and also on spatial<br>Fig. 8.

the distribution function entering Eq. (24). The reason is that equation such as the full band Monte Carlo (12). An example  $R_1$  starts to become appreciably large only at relatively high of the distribution at high ener  $R_1$  starts to become appreciably large only at relatively high of the distribution at high energies is given in Fig. 9 for a energies, as shown in Fig. 8. Typically, in silicon, ionization constant electric field. Figur becomes important only for electron energies of 3 eV above tering rate in silicon at room temperature as a function of



**Figure 8.** Impact ionization rate  $\alpha_t$  (multiplied by  $\hbar$ ) as a function of conduction electron energy according to the theory of Kane (25). Re- The special status of hot electrons in semiconductor devices



and temporal changes of the electric field and can only be An even greater numerical problem is the calculation of reliably obtained from a full band solution of the Boltzmann<br>the distribution function entering Eq. (24). The reason is that equation such as the full band Monte Carl constant electric field. Figure 9 also shows the phonon scatconduction band energies. Note that this rate becomes of the order of  $10^{14}$  s<sup>-1</sup> at energies above 1.5 eV.

> A discussion of all of these complexities and the corresponding results for  $\alpha_r$  are given in Refs. 15, 27. The best results are obtained for theories of  $R<sub>I</sub>$  a´ la Kane and for distributions from full band Monte Carlo integrations of the Boltzmann equation (25). Typical theoretical results of  $\alpha_r$  are shown in Fig. 10.

> The presence of layers of different semiconductors, as occurs in quantum well structures and superlattices, adds another dimension to the science and engineering of impact ionization and has been discussed extensively in the literature. Examples are given in Refs. (29) and (30).

> A simplified approach of great usefulness and parametrized expressions for  $\alpha_r$  have been derived by Baraff and others using his theory (7,31). These are excellent for estimates and for an appreciation of contributory physical parameters. Note, however, that all the simplified analytical expressions given in most textbooks for the threshold, phonon scattering mean free path, etc. are quantitatively incorrect and cannot replace the integration of Boltzmann's equation including the band structure.

## **HOT ELECTRONS IN DEVICES**

printed with permission,  $© 1967$  by the American Physical Society. arises from the time and space dependences of electric field



**Figure 10.** Theoretical electron impact ionization coefficients  $\alpha_r$  vercon is much below the curve for electrons (factors of more than  $10$ ). Reprinted with permission,  $\circ$  1992 by the American Physical Society. The documentation of overshoot effects in silicon-based de-

PATT diodes, hot electron diodes and transistors, real-space field effect transistors (MOSFETs), involve hot electrons in their operation. Often, hot electrons are felt to cause great devices and may reduce some of their advantages. disadvantage because they reduce speed (current and velocity Impact ionization is an important limiting factor in field above. This large rate gives rise to dephasing of the wave of the ionization (32,38). function on the length scale of 0.003  $\mu$ m. Therefore it is possi-<br>As discussed above, the probability of impact ionization is predictions that hot electron effects will be scaled away soon significant ionization. have therefore often not come true. Since hot electron effects With a space-dependent electric field *F*(*z*) in the *z* direcin many variations. The contraction of the contraction of the equation like equation like

## **Hot Electrons in Field Effect Devices**

Field effect transistors exhibit a large number of hot electron effects. It has been known since the sixties (34) that velocity saturation is important in these devices. The saturation was at first only encountered close to the drain, in the so-called pinchoff region (7). As the device sizes decreased, the velocity saturation spread all over the channel, at least for the highest drain voltages used (7). This effect reduces some of the figures of merit of the transistors (as, e.g., the transconductance) and was therefore seen as an unwelcome side effect; it was simulated by use of Eq. (16) and Eq. (15) or similar equations but with space-dependent electric fields. This local dependence on a varying electric field is, of course, only valid if the field var-**Figure 10.** Theoretical electron impact ionization coefficients  $\alpha_r$  ver-<br>sus 1/F for constant electric fields F and various materials after Bude the nonlocal velocity overshoot or hallistic components. These sus 1/F for constant electric fields F and various materials after Bude<br>and Hess (Ref. 25). Solid line: GaAs; dashed line: InAs; dot-dashed<br>line: InP; and dotted line: Ga<sub>0.43</sub>In<sub>0.57</sub>As. The electron ionization coeffi-<br>c tron ionization coefficients while the hole ionization coefficient for sili-<br>contribute to higher device speed. This has been proven in<br>con is much below the curve for electrons (factors of more than 10) MOSFETs, as discus

vices is a nontrivial task, since they always appear in connection with velocity degradation in other regions of the devices, and they are small (around a factor of 2 for  $T_{\rm L}$  = 300 K). and carrier concentrations. These dependences require special Overshoot effects are larger in III–V compound field effect care in the theory of average velocity (overshoot real-space transistors such as metal–semiconductor care in the theory of average velocity (overshoot, real-space transistors such as metal–semiconductor transistors (MES-<br>transfer transport including abrunt interfaces) and impact FETs). Ordinary MESFETs exhibit much scatte transfer, transport including abrupt interfaces) and impact FETs). Ordinary MESFETs exhibit much scattering in the ionization The nonlocality of these effects deserves special at conducting channel due to the charged donor ionization. The nonlocality of these effects deserves special at-<br>tention (32) Consistency with Gauss's law also needs to be addition to the always present scattering by the polar optical tention (32). Consistency with Gauss's law also needs to be addition to the always present scattering by the polar optical satisfied. In fact, numerical solutions of Poisson's equation phonons  $(3,7)$ . The overshoot effec satisfied. In fact, numerical solutions of Poisson's equation phonons (3,7). The overshoot effects are therefore more pro-<br>are a fixed part of any predictive device simulation. The field nounced in modulation-doped field e are a fixed part of any predictive device simulation. The field nounced in modulation-doped field effect transistors (MOD-<br>of hot electrons in devices is therefore a vast one and cannot. FET), which contain the dopants in of hot electrons in devices is therefore a vast one and cannot FET), which contain the dopants in a layer of a different<br>be reviewed within this limited space. For a general apprecia-<br>semiconductor (e.g., AlGaAs) neighbori be reviewed within this limited space. For a general apprecia-<br>tion the reader is referred to discussions of Gunn devices. IM- GaAs) as described in Ref. 35. These transistors exhibit, tion the reader is referred to discussions of Gunn devices, IM- GaAs) as described in Ref. 35. These transistors exhibit,<br>PATT diodes, hot electron diodes and transistors, real-space therefore, a significant speed advantag transfer devices, and avalanche photodiodes in Ref. 18. All of shown by numerous works (36,37). Typical values of the over-<br>these devices are based on hot electron effects. Many of the shoot in such devices, as deduced fro these devices are based on hot electron effects. Many of the shoot in such devices, as deduced from Monte Carlo simula-<br>most important devices, such as metal-oxide-semiconductor tions, correspond to those shown in Fig. 7. most important devices, such as metal–oxide–semiconductor tions, correspond to those shown in Fig. 7. We note that real-<br>field effect transistors (MOSFETs), involve hot electrons in space transfer can, of course, be also o

saturation), lead to degradation and aging of devices (33), and effect transistors, since its presence usually will distrurb decan cause various instabilities (e.g., through negative differ- vice operation. The theory of impact ionization in devices proential resistance). However, there are two counts in favor of ceeds along the lines discussed above. However, nonlocal efhot electrons in devices that have led to the continual involve- fects are of great significance because of the presence of ment of hot electrons in chip technology. For one, hot elec- rapidly varying electric fields in the conducting channels of trons lead to a large scattering rate by phonons as discussed field effect devices. One then needs to allow for dead spaces

ble to reach feature sizes down to 0.1  $\mu$ m without major tran-very small for electron energies below a certain energy in the sitions from classical to quantum transport. The second point conduction band. Of course, the minimum energy the electron in favor of hot electrons arises from the need for aggressive needs is the energy of the gap,  $E<sub>G</sub>$ . Even above this energy, designs, particularly with respect to switching speed. One the threshold for significant ionization is often not reached for needs to use the highest possible current densities, and this energies of two or three times *EG*, as can be seen from Kane's means in semiconductors also high electric fields. Frequent results in Fig. 8. This energy needs to be reached to start

are important in so many devices and of such variable conse- tion, the electron needs to traverse a certain distance *d* to quences, we will discuss here only major effects that appear reach effective threshold. Typically *d* can be obtained from an

$$
\int_{0}^{d} F(z) dz = cE_{\rm G}
$$
 (25)

where *c* is a constant determining the effective threshold (normally of the order of 2). Over such a distance, ionization canot occur, even if the electric field is very high. Ionization in very short field effect transistors with highly peaked electric fields is therefore smaller than one would expect from an integration of the ionization probability over all fields not counting the dead space of length *d*. This explains the fact that ionization is not a function of the local electric field alone (nonlocality).

Anisotropies of impact ionization, which have not been found for constant electric fields (23), can occur when ballistic acceleration over short distances is important, mainly because of anisotropies of the effective threshold (39). These further complicate the simulation of impact ionization in devices. It is the conviction of this author that a quantitative understanding of impact ionization in devices is only possible by a full band solution of the Boltzmann equation consistent with the solution of Poisson's equation, as can be done with various simulation tools (13,14). Some of the controversies in the literature can be tracked to oversimplified simulation.

The hot electron effects discussed above are reversible in the sense that after turning off the electric fields, the hot electrons cool down to the ambient temperature within picosec onds without any structural changes of the crystal lattice. However, hot electrons can also cause structural changes. A<br>pitter 12. Modulation response of quantum well laser diodes for<br>particularly well-known hot electron degradation occurs at<br>the MOSFET interface between the silico the MOSFET interface between the silicon and the silicon di-<br>oxide (33). This damage is linked to the breaking of silicon-<br>is weak, particularly at higher power levels. (b) Theory including hot hydrogen bonds that are always present at this interface. A electron effects (temperatures indicated above curves) shows excel-<br>clear proof was given by damage measurements involving the lent agreement with experiments (38 clear proof was given by damage measurements involving the isotope deuterium (40). When the silicon–hydrogen complex was replaced by silicon-deuterium, a much-reduced hot election degradation of MOSFETs was found, which has the ben-<br>eficial effect of increasing the device lifetime (41). A large earn therefore heats the quantum well elect

origin and different consequences from what they have in The quantum well electrons at low energy can then in turn<br>field effect devices. The electrons are here not heated by the absorb phonons and heat up themselves. This electric field but by other electrons propagating into the quan-<br>tum well and exhibiting suddenly high kinetic energy as A completely consistent calculation tum well and exhibiting suddenly high kinetic energy as A completely consistent calculation of these effects has<br>shown in Fig. 11. These electrons, originating from outside been made (43) and shows that the modulation of e



tion and acquiring significant kinetic energy (in the GaAs). vices.



is weak, particularly at higher power levels. (b) Theory including hot

phonons (within about  $10^{-13}$  s). These phonons cannot propa-Hot Electrons in Quantum Well Laser Diodes<br>
Hot Electrons in quantum well laser diodes have a different<br>
Hot electrons in quantum well laser diodes have a different<br>
vivior rise to a nonequilibrium (heated) phonon distribu giving rise to a nonequilibrium (heated) phonon distribution. absorb phonons and heat up themselves. This gives rise to a

shown in Fig. 11. These electrons, originating from outside been made (43) and shows that the modulation of electron<br>the well, can now transfer their energy in essentially two density in quantum well laser diodes is always the well, can now transfer their energy in essentially two density in quantum well laser diodes is always accompanied<br>ways to the electrons in the quantum well. For one, they can by a modulation of the electron temperature ways to the electrons in the quantum well. For one, they can by a modulation of the electron temperature and therefore transfer the energy through direct electron-electron interaction of the laser performance and modulatio influences the laser performance and modulation response tion (electron–hole interactions can also be important in laser sensitively through very small temperature rises. While field diodes because of the presence of both electrons and holes effect devices operate at electron temperatures of several thousand kelvins caused by the heating of the electric field, laser diodes cease to operate for dynamic electron heating of a few kelvins, as shown in Fig. 12, which depicts the modulation response of a typical semiconductor laser diode. The static heating is also important in lasers and degrades their performance. For the static case electron temperatures AlGaAs GaAs around 100 K above room temperature may be tolerated— **Figure 11.** Electron propagating over a semiconductor heterojunc- still much less than the  $T_c$  values reached in field effect de-

- 
- 2. W. Shockley, *Bell Syst. Tech. J.,* **30**: 990–1040, 1951; *Solid State* 1994. *Electron.,* **2**: 35–67, 1961. 27. M. V. Fischetti, S. E. Laux, and E. Crabbe, in K. Hess, J. P.
- NJ: Prentice-Hall, 1988. New York: Plenum, 1996, pp. 475–480.
- *Physics of Nonlinear Transport in Semiconductors, New York: Ple-*
- 
- 
- 6. Z. S. Gribnikov, K. Hess, and G. A. Kosinovsky, J. Appl. Phys.,<br>
77: 1337–1373, 1995.<br>
7. S. M. Sze, Physics of Semiconductor Devices, New York: Wiley,<br>
8. I. G. Buch, JEEE, Trans. Electron, Devices, FD-19: 659, 659, 31
- 31. G. A. Baraff, *Phys. Rev.,* **128**: 2507–2517, 1962. 8. J. G. Ruch, *IEEE Trans. Electron Devices,* **ED-19**: 652–659,
- 510, 1987. 9. P. D. Yoder and K. Hess, in N. Balkan (ed.), *Negative Differential Resistance and Instabilities in 2-D Semiconductors,* New York: 33. C. Hu et al., *IEEE Trans. Electron Devices,* **ED32**: 375–385, 1985. Plenum, 1993, pp. 99–107. 34. J. A. Cooper and D. F. Nelson, *J. Appl. Phys.,* **54**: 1445, 1983.
- 10. K. Brennan and K. Hess, *IEEE Electron Device Lett.,* **7**, 86–88, 35. T. Mimura, K. Taniguchi, and C. Hamaguchi, *Semicond. Sci.* 1986. *Technol.,* **7**: 379–381, 1992.
- 11. K. Hess, in N. Balkan (ed.), *Hot Electron Physics and Devices,* 36. H. Morkoc and P. M. Solomon, Modulation-doped field-effect tran-Oxford Univ. Press, 1997, pp. 13–33. sistors, *IEEE Spectrum,* **21**(2): 28–35, 1984.
- 12. H. Shichijo and K. Hess, *Phys. Rev. B,* **23**: 4197–4207, 1981. 37. I. C. Kizilyalli et al., in H. Daemblees (ed.), *Modulation-Doped*
- Full Band and Beyond, Boston: Kluwer Academic, 1991, pp. 350–355. 1–26. 38. J. M. Higman, I. C. Kizilyalli, and Karl Hess, *IEEE Electron De-*
- 
- 15. Z. Selmi et al., *IEDM Tech. Dig.,* 1995, pp. 293–296. 39. T. Kunikiyo, *J. Appl. Phys.,* **75**: 297 (1994).
- *Electronics, Vol. 2, New York: Academic Press, 1981, pp. 67-103.*
- 
- *Lett.,* **18**: 81–83, 1997. 18. K. K. Ng, *Complete Guide to Semiconductor Devices,* New York: McGraw-Hill, 1995. 42. E. Takeda, C. Y. Yang, and A. Miura-Hamada, *Hot-Carrier Ef-*
- 19. C. J. Stanton, D. W. Bailey, and K. Hess, *IEEE J. Quantum Elec-* fects in MOS Devices, New York: Academic Press, 1995.
- 140, 1998. 20. G. J. Iafrate and K. Hess, *Proc. IEEE,* 519–532, 1988.
- 21. J. Y. Tang and K. Hess, *IEEE Trans. Electron Devices,* **ED29**: K. HESS 1906–1910, 1982. University of Illinois 22. M. S. Shur and L. F. Eastman, *IEEE Trans. Electron Devices,*
- **ED26**: 1677–1683, 1979.
- 23. G. E. Stillman, V. M. Robbins, and K. Hess, Proc. 4th Int. Conf. Hot Electrons Semiconductors, **HIGH-FREQUENCY.** See MILLIMETER WAVE MEA- *Inst. Phys.,* **134B** - **C**: 241–246, 1985. SUREMENT.
- **BIBLIOGRAPHY** 24. L. V. Keldysh, *Soviet Phys. JETP,* **21**: 1135, 1965.
	- 25. E. O. Kane, *Phys. Rev. B,* **159**: 624, 1967.
- 1. E. J. Ryder, *Phys. Rev.,* **90**: 766–769, 1953. 26. P. D. Yoder and K. Hess, *Semicond. Sci. Technol.,* **9**: 852–854,
- 3. K. Hess, *Advanced Theory Semicond. Devices,* Englewood Cliffs, Leburton, and U. Ravaioli (eds.), *Hot Carriers in Semiconductors,*
- 4. G. Bauer, in D. K. Ferry, J. R. Barker, and C. Jacoboni (eds.), 28. J. D. Bude and K. Hess, Impact ionization, *J. Appl. Phys.,* **72**: num, 1979, pp. 175–224. *cond. Sci. and Technol.,* **7**: 506–508, 1992; N. Sano, M. Tomizawa, and A. Yoshi, in K. Hess, J. P. Leburton and U. Ravaioli (eds.), 5. D. K. Ferry, *Semiconductors*, New York: Plenum, 1996, pp. *Hot Carriers in Semiconductors*, New York: Plenum, 1996, pp.  $\frac{337-342}{\ldots}$ .
	-
	-
	-
	- 1972. 32. K. Kim, K. Hess, and F. Capasso, *Appl. Phys. Lett.,* **51**: 508–
		-
		-
		-
		-
- 13. S. E. Laux and M. V. Fischetti, in *Monte Carlo Device Simulation: Field-Effect Transistors,* Piscataway, NJ: IEEE Press, 1990, pp.
- 14. DEGAS, http://www.ise.ch. *vice Lett.,* **9**: 399–401, 1988.
	-
- 16. D. K. Ferry, K. Hess, and P. Vogl, in N. G. Einspruch (ed.), *VLSI* 40. J. W. Lyding, K. Hess, and I. C. Kizilyalli, *Appl. Phys. Lett.,* **68**:
- 17. H. M. J. Boots et al., *Appl. Phys. Lett.,* **57**: 2446–2448, 1990. 41. I. C. Kizilyalli, J. W. Lyding, and K. Hess, *IEEE Electron Device*
	-
	- *tron.,* **24**: 1614–1627, 1988. 43. M. Grupen and K. Hess, *IEEE J. Quantum Electron.,* **34**: 120–